

Technique for Advanced Materials

Multifunctional Thermal Stage

Micro-STS 1200

Aug. 2024





Units Technology Co., Ltd.

UNITS Tech is a high-tech science facilities manufacturer. According to the new two-dimensional materials research demand during the sub-nano time, we have invented visualizing CVD devices for observing and recording the growth process of two-dimensional materials.



Micro-STS 1200 Introduction



Micro-STS 1200 - What is it



Micro-STS 1200 is a multifunctional Thermal Stage combined with traditional tube furnaces and traditional thermal stage, realizing the combination with In-situ synthesis and In-situ optical characterization.

Micro-STS 1200 – Technological advantages





Visualization system

- Compatible with microscopy and spectroscopy
- Highest magnification of 500x. Resolution≈1.5 µm

Suitable for different gases

- Nitrogen, Argon, Oxygen, gas mixtures etc.
- Available for LPCVD

Compact size Large heating field

- Light weight, flexible methodology and inexpensive price
- Volume: 175*80*50mm
 Heating Zone: 40*10*10mm

High efficiency High precision

- Fast temperature raising/falling rate up to 100°C/min
- Precisely 0.5°C control from RT to maximum limiting temperature 1100°C

Customized sample location

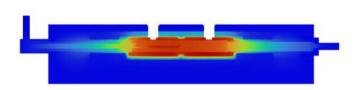
- Precise control of the sample location
- Easy to accomplish annealing and hardening of the materials

Safe and low energy consumption

- Surface temperature lower than 40°C
- Power consumption lower than 0.4kW

1. Visualization system

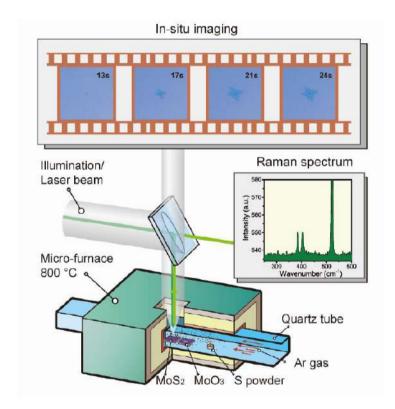




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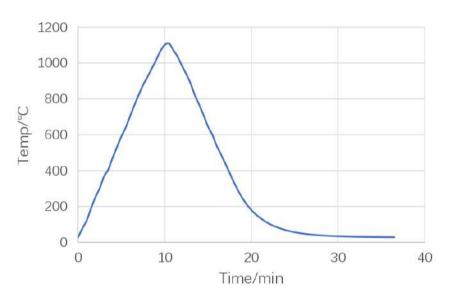
- Compatible with microscopy
- Highest objective lens magnification of 50X
- Uniform heating field distribution
- Low surface temperature
- High Numerical Apertures
- Wide transmittance spectrum



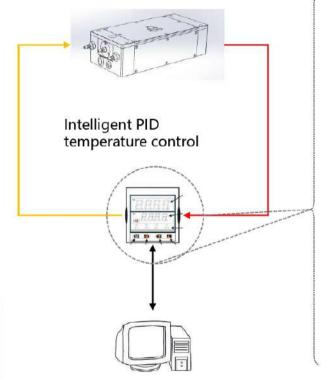


Compatible with spectroscopy

2. High efficiency, high precision



Temperature raising/falling rate ≤100°C/min
(It is recommended to control the heating rate at temperatures above 600°C to within 60°/min.)
Temperature Control Accuracy = ±0.5°C
Temperature Measurement Accuracy=±0.1°C







Yu Dian Tech



Omron



Eurotherm

3. Suitable for different gases

Inter gases

Oxidizing atmosphere

Gas mixtures

LPCVD

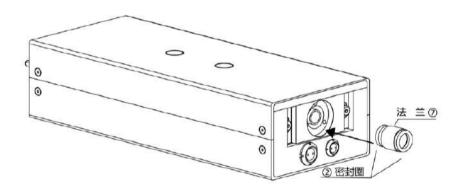


- Self-developed water-gas transition system
- Suitable for 2 gas channels





- Quartz material
- Good corrosion resistance

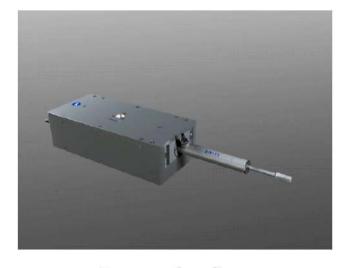


- Multiple seal structure
- LPCVD

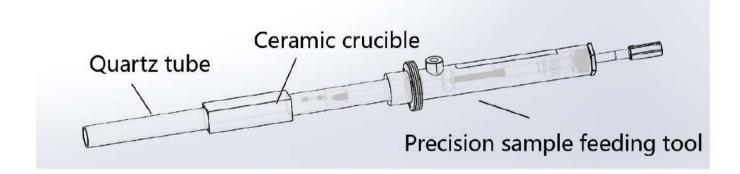
4. Customized sample location







Source feeding



- Precisely control the sample location by pushing in/pulling out
- Easy to realize annealing/quenching of the materials
- Moving stroke=80mm

5. Compact size, large heating field





Size: 175*80*50mm

Heating zone: 40*10*10mm



Size: 220*80*50mm

Heating zone: 80*10*10mm

Ceramic crucible

Size: 18×5×1.6mm

6. Safe and low energy consumption

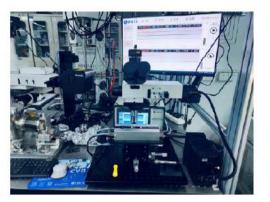




- Circulating Cooling Furnace Design
 The water circulating cooling system ensures
 that the stage surface temperature close to the
 room level
- Low energy consumption
 The power of the whole system lower than
 1.5kW
- Inside warning system
 The built-in alarm system ensures the experiment is safe and controllable

Project deliverables





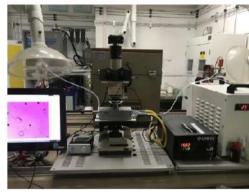
BGI-graphene Academician Liu Zhongfan



PKU-CNT Academician Zhang Jin



USTB-TMDC Academician Zhang Yue



Fudan University-TNAs Academician Liu Yunqi



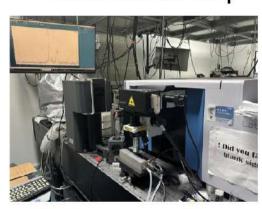
BIT—MoTe₂



Hunan University—WS₂



HUST--Disulfide

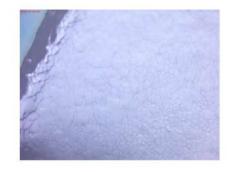


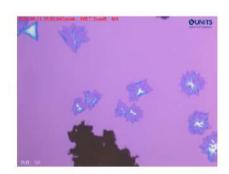
NJU-- CVD+ Raman

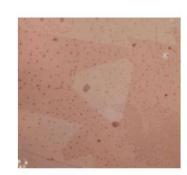


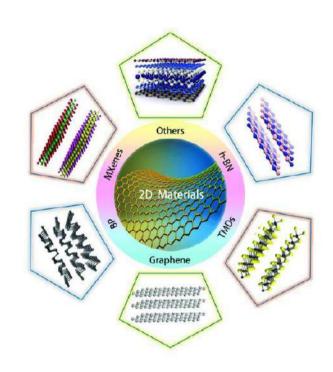
Applied materials

- $\sqrt{\text{Graphene}}$ $\sqrt{\text{MoS}_2}$ $\sqrt{\text{MoTe}_2}$ $\sqrt{\text{MoO}_3}$
- $\sqrt{\text{CNT}}$ $\sqrt{\text{WS}_2}$ $\sqrt{\text{WO}_3}$ $\sqrt{\text{Bi}_2\text{O}_2\text{Se}}$
- $\sqrt{}$ Rare earth material $\sqrt{}$ Copper $\sqrt{}$ More to explore











Micro-STS 1200

Application

Application1 High-Temperature In Situ Investigation of CVD





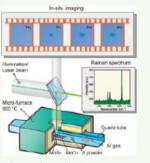
pubs acs.org/acsaelm Article

High-Temperature In Situ Investigation of Chemical Vapor Deposition to Reveal Growth Mechanisms of Monolayer Molybdenum Disulfide

Hao Xue, Guozheng Wu, Bojin Zhao, Di Wang, Xiaoming Wu, and Zhanggui Hu



ABSTRACT: In situ investigation of chemical vapor deposition (CVD) is of critical importance to understanding growth mechanisms of transition-metal dichalcogenides (TMDs) and to develop technologies for growing high-quality monolayer single crystals. However, the in situ investigation is still a great challenge in practice, because TMD CVD growth is conducted at a high temperature with a reduction environment. In this work, we developed an in situ investigation system for CVD growth and presented real-time observations of monolayer MoS₂ deposition on the SiO₂/Si substrate. We discovered that monolayer MoS₂ should be grown via the vapor-state precursor reaction and crystallized from the prenucleation sites on a substrate, an intermediate-phase MoO₂ was essential for the nucleation seeding, but the population density should be controlled, and a high-concentration S vapor promoted the in-plane epitaxial growth of MoS₂; hence, it was of great benefit to obtain a high-quality monolayer with a compact shape.



KEYWORDS: 2D materials, in situ investigation, Raman spectroscopy, chemical vapor deposition, crystal growth mechanism, microfurnace, transition-metal dichalcogenides



Micro-STS 1200 DEMO



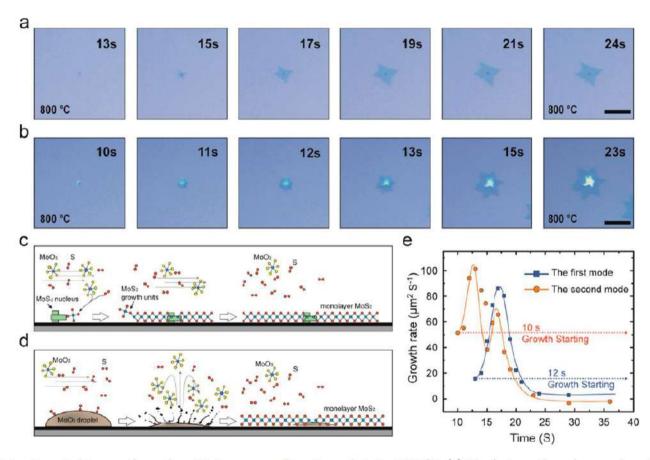


Figure 3. In situ optical images of monolayer MoS_2 grown on the epitaxy substrate at 800 °C. (a) The first growth mode: monolayer MoS_2 growth around a nucleation site. The scale bar is $15 \ \mu m$. (b) The second growth mode: monolayer MoS_2 growth from MoO_3 droplets. The scale bar is $35 \ \mu m$. (c) Schematic represents monolayer MoS_2 grown around a MoS_2 nucleation site, where the growth is fed by the vapor-state MoS_2 from a MoO_3 droplet, where the growth is fed by the liquid droplet. (e) Time-dependent growth rates of monolayer MoS_2 by two modes. Two growth modes were recorded simultaneously in one substrate under a flow rate of 50 sccm.



The study of the intermediate precursors in the MoS₂ growing process

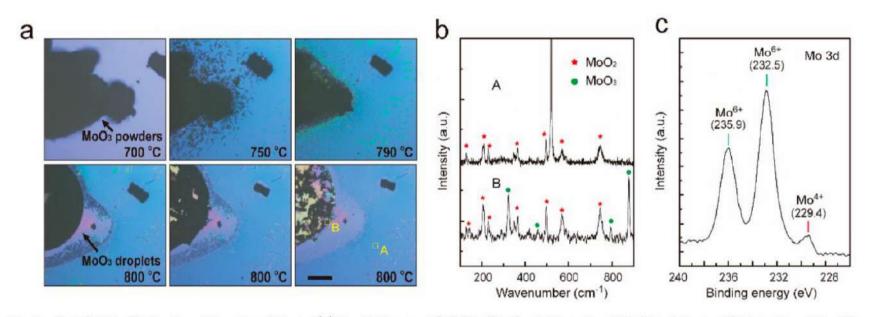


Figure 4. Suboxide MoO₂ deposition on substrate. (a) In situ images of MoO₂ film deposition on a SiO₂/Si substrate at high temperature. The scale bar is 80 μ m. (b) Ex situ Raman spectra of the film and the residual droplet, collected from the points marked by yellow squares in (a). (c) Ex situ XPS spectrum of the deposited film with the X-ray spot size of 300 μ m.

Application2 Automated growth of CNT



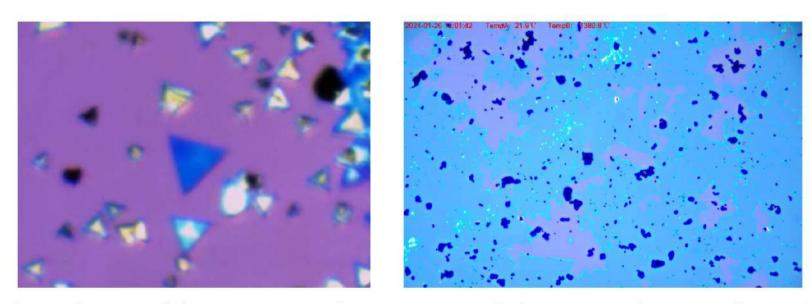




The research group of Academician Zhang Jin of Peking University has developed the "Peking University Carbon Nanotube Automatic Growth Platform" based on our company's products, which realizes 24-hour fully automatic, repeatable, and high-quality carbon nanotube preparation (30 furnaces/day), which is 10 times more efficient than that of traditional tube furnaces.

Application3 The growth of the TMDC

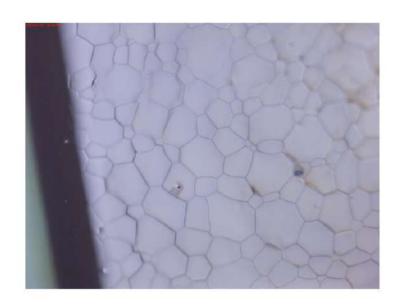


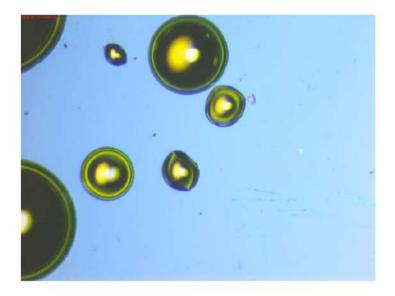


A doctor from a well-known university has never succeeded in growing the target object. After observing and recording the growth process through Micro-STS1200, he found that the target object has been generated during the growth process, but etched over time. Subsequently, through process adjustment, combined with the Micro-STS1200, and by observing and controlling various parameters while experimenting, the target material was successfully grown.

Application4 The observation of the metal transition







The Micro-STS1200 utilizes the characteristics of visualization, annular thermal field, controllable heating and cooling rates, and multi-atmosphere environments to observe, record and analyze the high-temperature phase change processes of metals and other substances in different environments.